

General Information

The **data collection module (DCM)** is an optional feature which helps to collect and log measurement data of several sensors which need to be installed inside the machine. This data can help to **avoid unplanned tool down situations** due to the immediate detection of unusual deviation for a certain measurement value. Furthermore, the system helps to detect and to solve failures faster which has a **positive impact on the uptime** of the machine.

Limits for each data value can be set to detect a discrepancy instantly. In addition, it's possible to set a frequency of data logging so the data can be checked in a graph for a certain time frame (see figure 2). Figure 1 shows the data which will be measured, displayed and logged:

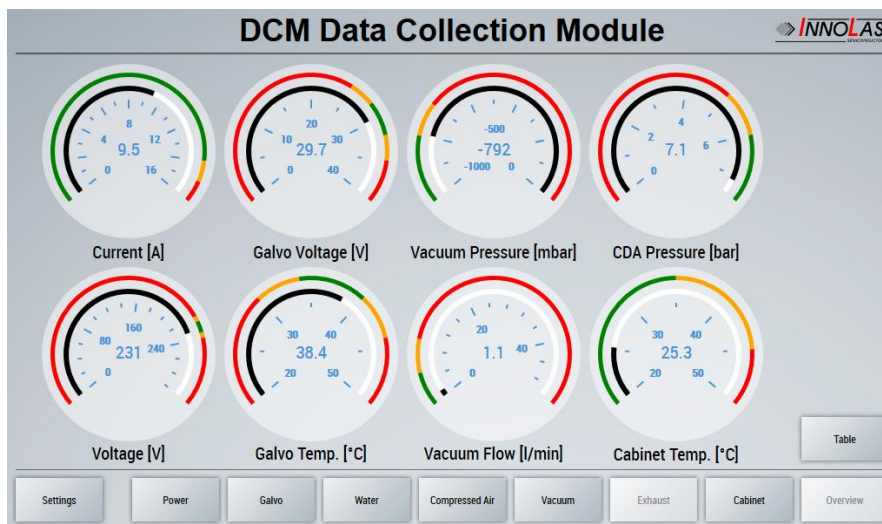


Figure 1: Overview of all measurement values on the screen

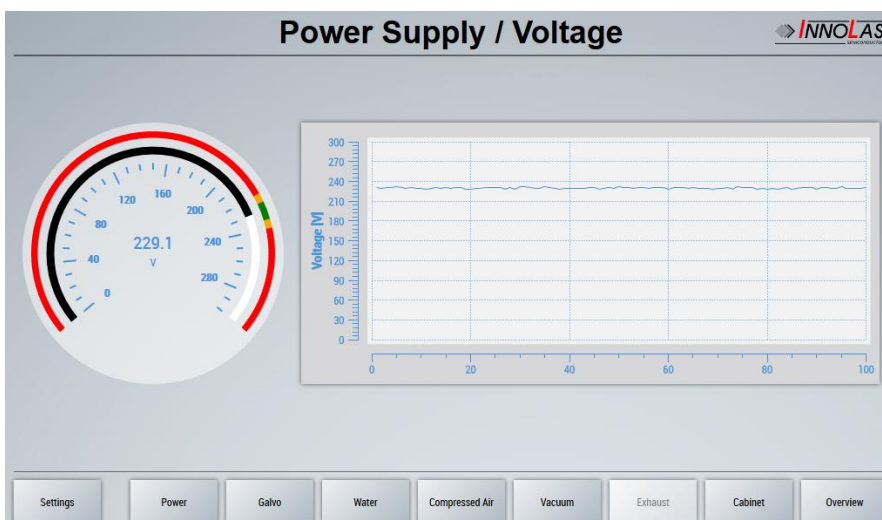


Figure 2: Display of the actual measurement value of the voltage (left side) and a trend of the last 100 measurements (right side)

Mounting Position and Availability

In figure 3 you can see the position of the DCM option in an IL3000 wafer marking system

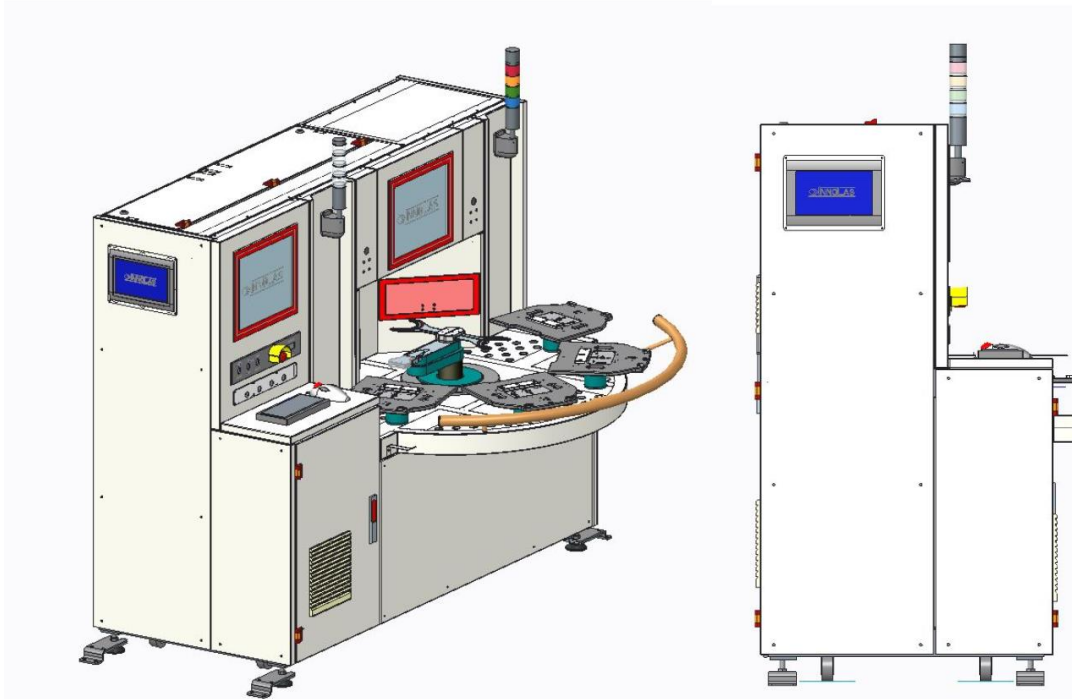


Figure 3: Example for the mounting position at an InnoLas IL3000

The DCM option will be available for all InnoLas Wafer Marking System starting Q4/2020. It can be upgraded in the field on-site as an upgrade or purchased with new equipment.

Technical Data and Measurement Accuracy

Measurement Point	Parameter	Unit	Accuracy
Supplies	Current	mA	± 50 mA
Supplies	Voltage	V	± 0,75 V
Ext. Water	Temperature	°C	± 1°C
Ext. Water	Flow	l/min	± 0,3 l/min
CDA	Pressure	bar	± 0,2 bar
CDA	Flow	l/min	± 2 l/min
Vacuum	Pressure	bar	± 30 mbar
Vacuum	Flow	l/min	± 0,5 l/min
Galvo-Scanner	Voltage	V	± 30 mV
Galvo-Scanner	Temperature	°C	± 0,5 °C
Cabinet	Temperature	°C	± 0,5 °C
Chiller (int. Water)	Temperature	°C	± 1°C
Chiller (int. Water)	Flow	l/min	± 0,3 l/min